



08-11-04

Patent Application
2771-506ITW
AF
1753

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:

Applicant: ARNO, Jose, et al.

Application No.: 10/065,219

Date Filed: September 26, 2002

Title: SYSTEM FOR IN-SITU
GENERATION OF FLUORINE
RADICALS AND/OR
FLUORINE-CONTAINING
INTERHALOGEN (XF_n)
COMPOUNDS FOR USE IN
CLEANING SEMICONDUCTOR
PROCESSING CHAMBERS

Docket No.: ATMI-506 (7486)

Examiner: WONG, Edna

Art Unit: 1753

Confirmation No.: 9419

Customer No.: 25559

EXPRESS MAIL CERTIFICATE

I hereby certify that I am mailing the attached documents to the Commissioner for Patents on the date specified, in an envelope addressed to Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, and Express Mailed under the provisions of 37 CFR 1.10.

Joanna Joslyn

August 10, 2004

Date

EO 002408676 US

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RESPONSE TO JULY 28, 2004 OFFICE ACTION
IN UNITED STATES PATENT APPLICATION NO. 10/065,219

Mail Stop AF
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

This responds to the July 28, 2004 Office Action in the above-identified application.

Please amend the claims of the application as set out in the following **Section I (Amendments to the Claims)**.

Please amend the drawings of the application as set out in the following **Section II (Amendments to the Drawings)**.

Remarks addressing the various issues raised in the July 28, 2004 Office Action are set out in **Section III (Remarks)** hereof.